

PATENT
97-CT-174IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
RAFFAELE ZAMBRANO
Serial No.: 09/191,743
Filed: November 13, 1998
For: IN-SITU DEPOSITION AND
DOPING PROCESS FOR POLY-
CRYSTALLINE SILICON LAYERS
AND THE RESULTING DEVICE

Group Art Unit: 2815

Examiner: M. Warren

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7-26-99

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AMENDMENT AND ELECTION

VIA FACSIMILE (703) 308-7722
Assistant Commissioner for Patents
Washington, D.C. 20231
ATTN: Matthew Warren

Sir:

In response to the Office Action dated July 19, 1999, in connection with the
above-identified application, please enter and consider the following amendment and remarks.

I hereby certify that this correspondence
is being facsimile transmitted to the
United States Patent and Trademark

Office, on

7/22/99
Date of TransmissionStephen Bongini
Applicant, Assignee, or Representative

Signature

Date

7/22/99